

## UNITED STATES PATENT AND TRADEMARK OFFICE

eer

UNITED STATES DEPARTMENT OF COMMERCE United States Patent and Trademark Office Address: COMMISSIONER FOR PATENTS P.O. Box 1450 Alexandria, Virginia 22313-1450 www.uspto.gov

APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/705,347	11/08/2003	Catherine B. Labelle	0180151	4624
25700 7590 01/30/2008 FARJAMI & FARJAMI LLP			EXAMINER	
26522 LA ALAMEDA AVENUE, SUITE 360			CHEN, KIN CHAN	
MISSION VIE	JO, CA 92691	•	ART UNIT	PAPER NUMBER
		•	MAN DATE	DELIVERY MODE
		. •	MAIL DATE	DELIVERY MODE
			01/30/2008	PAPĘR

Please find below and/or attached an Office communication concerning this application or proceeding.

The time period for reply, if any, is set in the attached communication.

## Advisory Action Before the Filing of an Appeal Brief

Application No.	Applicant(s)		
10/705,347	LABELLE ET AL.		
Examiner	Art Unit		
Kin-Chan Chen	1792		

The MAILING DATE of this communication appears on the cover sheet with the correspondence address
THE REPLY FILED 22 January 2008 FAILS TO PLACE THIS APPLICATION IN CONDITION FOR ALLOWANCE.
1. The reply was filed after a final rejection, but prior to or on the same day as filing a Notice of Appeal. To avoid abandonment of this application, applicant must timely file one of the following replies: (1) an amendment, affidavit, or other evidence, which places the application in condition for allowance; (2) a Notice of Appeal (with appeal fee) in compliance with 37 CFR 41.31; or (3) a Request for Continued Examination (RCE) in compliance with 37 CFR 1.114. The reply must be filed within one of the following time periods:
a) The period for reply expires 3 months from the mailing date of the final rejection.
b) The period for reply expires on: (1) the mailing date of this Advisory Action, or (2) the date set forth in the final rejection, whichever is later. In no event, however, will the statutory period for reply expire later than SIX MONTHS from the mailing date of the final rejection.
Examiner Note: If box 1 is checked, check either box (a) or (b). ONLY CHECK BOX (b) WHEN THE FIRST REPLY WAS FILED WITHIN TWO MONTHS OF THE FINAL REJECTION. See MPEP 706:07(f).
Extensions of time may be obtained under 37 CFR 1.136(a). The date on which the petition under 37 CFR 1.136(a) and the appropriate extension fee have been filed is the date for purposes of determining the period of extension and the corresponding amount of the fee. The appropriate extension fee under 37 CFR 1.17(a) is calculated from: (1) the expiration date of the shortened statutory period for reply originally set in the final Office action; or (2) as set forth in (b) above, if checked. Any reply received by the Office later than three months after the mailing date of the final rejection, even if timely filed, may reduce any earned patent term adjustment. See 37 CFR 1.704(b).  NOTICE OF APPEAL
2. The Notice of Appeal was filed on A brief in compliance with 37 CFR 41.37 must be filed within two months of the date of filing the Notice of Appeal (37 CFR 41.37(a)), or any extension thereof (37 CFR 41.37(e)), to avoid dismissal of the appeal. Since a Notice of Appeal has been filed, any reply must be filed within the time period set forth in 37 CFR 41.37(a).
AMENDMENTS
3. The proposed amendment(s) filed after a final rejection, but prior to the date of filing a brief, will <u>not</u> be entered because (a) They raise new issues that would require further consideration and/or search (see NOTE below); (b) They raise the issue of new matter (see NOTE below);
(c) They are not deemed to place the application in better form for appeal by materially reducing or simplifying the issues for appeal; and/or
(d) ☐ They present additional claims without canceling a corresponding number of finally rejected claims. NOTE: (See 37 CFR 1.116 and 41.33(a)).
4. The amendments are not in compliance with 37 CFR 1.121. See attached Notice of Non-Compliant Amendment (PTOL-324).  5. Applicant's reply has overcome the following rejection(s):
6. Newly proposed or amended claim(s) would be allowable if submitted in a separate, timely filed amendment canceling the non-allowable claim(s).
7. For purposes of appeal, the proposed amendment(s): a) will not be entered, or b) will be entered and an explanation of how the new or amended claims would be rejected is provided below or appended.  The status of the claim(s) is (or will be) as follows:  Claim(s) allowed:
Claim(s) objected to: Claim(s) rejected:
Claim(s) withdrawn from consideration:  AFFIDAVIT OR OTHER EVIDENCE
8. The affidavit or other evidence filed after a final action, but before or on the date of filing a Notice of Appeal will <u>not</u> be entered because applicant failed to provide a showing of good and sufficient reasons why the affidavit or other evidence is necessary and was not earlier presented. See 37 CFR 1.116(e).
9. The affidavit or other evidence filed after the date of filing a Notice of Appeal, but prior to the date of filing a brief, will <u>not</u> be entered because the affidavit or other evidence failed to overcome <u>all</u> rejections under appeal and/or appellant fails to provide a showing a good and sufficient reasons why it is necessary and was not earlier presented. See 37 CFR 41.33(d)(1).
10. ☐ The affidavit or other evidence is entered. An explanation of the status of the claims after entry is below or attached.  REQUEST FOR RECONSIDERATION/OTHER
11. The request for reconsideration has been considered but does NOT place the application in condition for allowance because: see the attached sheet.
12 Note the attached Information Displacure Statement/s) (BTO(SD(08) Denor No/s)
13. Other:
Kin-Chan Chen

Primary Examiner Art Unit: 1792

## Response to Request-for-reconsideration-after-final

Applicant has argued that Colombo fails to disclose perform a nitridation process immediately after etching. It is not persuasive. Applicant has argued that Colombo does not disclose performing a nitridation process immediately after the step of etching the gate electrode layer and the high-k dielectric layer. It is not persuasive. Colombo [0026) discloses that the process steps in exemplary method in Fig, 4 may occur **in different orders.** Hence, it includes performing nitridation process immediately after the step of etching the gate electrode layer and the high-k dielectric layer as claimed in order to not to exposed to any contamination.

Applicant has argued that there is no reason to combine Alers or Tu with Colombo to apply the conventional nitridation of using plasma comprising nitrogen. It is not persuasive. As has been stated in the office action, Alers or Tu is only relied on to show the conventional nitridation method of applying plasma comprising nitrogen. Because it is a conventional method in the art of semiconductor device fabrication and because it is disclosed by Alers, Tu, hence, it would have been obvious to one with ordinary skilled in the art to apply said nitridation method in the process of Colombo in order to efficiently carry out the nitridation process.

The examiner recognizes that obviousness can only be established by combining or modifying the teachings of the prior art to produce the claimed invention where there is some teaching, suggestion, or motivation to do so found either in the references themselves or in the knowledge generally available to one of ordinary skill in the art. See In re Fine, 837 F.2d 1071, 5 USPQ2d 1596 (Fed. Cir. 1988) and In re Jones, 958 F.2d 347, 21 USPQ2d 1941 (Fed. Cir. 1992).

In this case, because it is a conventional method in the art of semiconductor device fabrication, it is in the knowledge generally available to one of ordinary skill in the art.

Application/Control Number:

10/705,347

Art Unit: 1792

Page 3

Applicant has also argued that there is no reason to combine Chang or Ballance or Aronowitz or Chang with Colombo. It is not persuasive. As stated in the office action, it is common in the art that the plasma process chamber may be used for performing both etching and nitridation because it is efficient and more cost effective. Chang'240 or Balance or Aronowitz or Chang'964 is simple the evidence to show that "performing both etching and nitridation in the same plasma process chamber" is the common knowledge well known in the art of semiconductor device fabrication, see the examiner's answer (06/07/2006, affirmed by BPAI), and the case law above.

In light of comments above, the rejections of obviousness under 35 U.S.C. 103(a) are maintained.

January 28,2008

TILLOHAN OMEN TILLU LITUMLUNTE